

saes SAES Pure Gas

The Technology of Pure Gas

AMBIENT INLINE PURIFIER 602 PURIFICATION MEDIA SPECIFICATION



0 – 500 slpm Ambient Inline Purifiers. For consistent gas quality and Impurity removal to pptV levels.



MicroTorr Ambient Inline Purifiers:

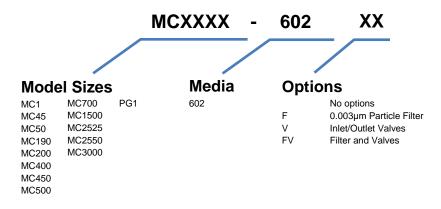
MicroTorr purifiers are the most complete and reliable solution for Point-of-Use (POU) gas purification. Combining model size with a selection of gas-specific purification materials, MicroTorr purifiers can be tailored to many different customer applications, while maintaining impurity removal to Part-Per-Billion (ppbV) levels or better. Optional valves and a 0.003 micron particle filter are available as well as custom subsystem configurations.

Competitive Advantages and Benefits:

- Reliability: Uncompromised process consistency and yield improvement.
- Performance: State-of-the-art purification technology, low pressure drop, and long lifetimes.
- Regenerability: Most MicroTorr media are factory regenerable, minimizing potentially hazardous waste.
- Quality: 316L stainless steel, Helium leak checked, and analytical testing to part-per-trillion (pptv) levels.
- Support: Lifetime estimation and regeneration service available through SAES Pure Gas Sales Network.

602 Media Purifier Properties					
Gases Purified CO					
Impurities Removed	H2O, O2, CO2, Acids, Bases, Organics, Refractory Compounds, Metals < 1 ppbV				
Particle Filtration	2 micron or 0.003 micron metal				
Vessel construction	Stainless Steel 316L, electropolished to 10 Ra				
Installation Orientation	Vertically with flow downward. Consult factory for other orientations.				
Leak Rating	1 x 10-9 atm cc/sec of He				
Operating temperature	-20 to 65 °C (-4 to 149°F) Lifetime may be effected at higher temperatures				
Lifetime	Contact SAES Pure Gas for application specific lifetime calculations				
Regenerability	Not Regenerable				
Certification	CE Certified to the Pressure Equipment Directive (PED) Designed in accordance with ASME				

Part Number Configuration:

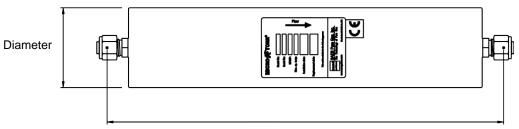




Purifier Sizes

Part Number	Maximum Flow (slpm)	Average Flow (slpm)	Operating Pressure (psig) Must be in gas phase	Inlet Connection	Outlet Connection	Diameter (inches [mm])	Face to Face Length (inches [mm])	Weight (lb. [kg])
Standard Models								
MC1-602F	5	0.5	1,000	1/4" MVCR	1/4" MVCR	1.5 [38.1]	3.31 [84.1]	< 0.7 [0.3]
MC45-602 MC45-602F	10	1.5	1,000	1/4" MVCR	1/4" MVCR	1.5 [38.1]	4.50 [114.3]	< 0.9 [0.4]
MC50-602F	10	1.5	1,000	1/4" MVCR	1/4" MVCR	1.5 [38.1]	5.00 [127.0]	< 0.9 [0.4]
MC190-602F	50	5	250	1/4" MVCR	1/4" MVCR	2.0 [50.8]	8.20 [208.3]	< 1.6 [0.7]
MC200-602F	50	5	250	1/4" MVCR	1/4" MVCR	2.0 [50.8]	6.30 [160.0]	< 1.8 [0.8]
MC400-602F	60	9	250	1/4" MVCR	1/4" MVCR	3.0 [76.2]	8.20 [208.3]	< 4.9 [2.2]
MC450-602F	75	10	250	1/4" MVCR	1/4" MVCR	3.0 [76.2]	7.94 [201.7]	< 4.1 [1.8]
MC500-602F	100	12	250	1/4" MVCR	1/4" MVCR	2.0 [50.8]	12.50 [317.5]	< 2.8 [1.2]
MC700-602F	120	25	250	1/4" MVCR	1/4" MVCR	3.0 [76.2]	10.00 [254.0]	< 7.6 [3.4]
MC1500-602F	250	40	250	1/2" MVCR	1/2" MVCR	3.0 [76.2]	18.20 [462.3]	< 8.0 [3.6]
MC2525-602F	300	80	250	1/4" MVCR	1/4" MVCR	4.0 [101.6]	17.30 [439.0]	< 13.0 [5.9]
MC2550-602F	500	80	250	1/2" MVCR	1/2" MVCR	4.0 [101.6]	17.60 [447.0]	< 13.0 [5.9]
MC3000-602 MC3000-602F	500	80	250	1/2" MVCR	1/2" MVCR	4.0 [101.6]	20.00 [508.0]	< 14.0 [6.4]

F = 0.003 micron particle filter



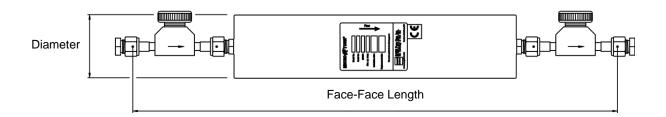
Face-Face Length



Purifier Sizes, with inlet and outlet isolation valves

Part Number	Maximum Flow (slpm)	Average Flow (slpm)	Operating Pressure (psig) Must be in gas phase	Inlet Connection	Outlet Connection	Diameter (inches [mm])	Face to Face Length with valves (inches [mm])	Weight with valves (lb. [kg])
Standard Mod	els							
MC1-602FV	5	0.5	1,000	1/4" FVCR	1/4" FVCR	1.5 [38.1]	8.91 [226.3]	< 2.6 [1.2]
MC45-602V MC45-602FV	10	1.5	1,000	1/4" FVCR	1/4" FVCR	1.5 [38.1]	10.10 [256.5]	< 2.9 [1.3]
MC50-602FV	10	1.5	1,000	1/4" FVCR	1/4" FVCR	1.5 [38.1]	10.60 [269.2]	< 2.9 [1.3]
MC190-602FV	50	5	250	1/4" FVCR	1/4" FVCR	2.0 [50.8]	13.80 [350.5]	< 3.7 [1.7]
MC200-602FV	50	5	250	1/4" FVCR	1/4" FVCR	2.0 [50.8]	11.90 [302.3]	< 3.8 [1.8]
MC400-602FV	60	9	250	1/4" FVCR	1/4" FVCR	3.0 [76.2]	13.80 [350.5]	< 6.8 [3.1]
MC450-602FV	75	10	250	1/4" FVCR	1/4" FVCR	3.0 [76.2]	13.54 [343.9]	< 6.0 [2.7]
MC500-602FV	100	12	250	1/4" FVCR	1/4" FVCR	2.0 [50.8]	18.10 [459.7]	< 4.5 [2.0]
MC700-602FV	120	25	250	1/4" FVCR	1/4" FVCR	3.0 [76.2]	15.60 [396.2]	< 9.6 [4.4]
MC1500-602FV	250	40	250	1/2" FVCR	1/2" FVCR	3.0 [76.2]	28.84 [732.5]	< 12.5 [5.8]
MC2525-602FV	300	80	250	1/4" FVCR	1/4" FVCR	4.0 [101.6]	23.20 [589.0]	< 15.0 [6.8]
MC2550-602FV	500	80	250	1/2" FVCR	1/2" FVCR	4.0 [101.6]	28.20 [716.0]	< 17.7 [8.0]
MC3000-602V MC3000-602FV	500	80	250	1/2" FVCR	1/2" FVCR	4.0 [101.6]	30.64 [778.3]	< 18.7 [8.5]
"U" Shaped Manifold								
PG1-602FV	15	10	250	1/4" FVCR	1/4" MVCR	2.0 [50.8]	13.80 [350.5]	< 5.1 [2.3]

F = 0.003 micron particle filter V = inlet and outlet isolation valves



Bypass and Dual Purifier Manifold Assemblies:

Many configurations are available; please consult the factory for details.



Other Purification Media's Available:

Media	Gases Purified	Impurities Removed				
202	CDA, O2, N2, Ar, He, Kr, Ne, Xe, H2, D2, CO2, N2O, NO, CF4	H2O to < 1 ppb				
203	CDA, O2, N2, Ar, He, Kr, Ne, Xe, H2, D2, N2O, NO, CF4	H2O, CO2 to < 100 ppt; Volatile Acids, Organics, Refractory Compounds to < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppb				
302	HCI, CI2, B2H6, BCI3, CCIH3, GeCl4, GeH4, H2S, H2Se, HBr, NF3, SiCl4, SiF4, SiH2Cl2, SiHCl3, SO2, CHCIF2, BF3,	H2O to < 1 ppb; Metals < 1 ppb				
403	N2, Ar, He, Kr, Ne, Xe, H2, CDA, O2	Volatile Acids, Organics, Refractory Compounds to <1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppb				
404	N2, Ar, He, Kr, Ne, Xe, H2, CDA, O2, CO2, C2H2, C3H6, C2H4, NH3, C2H6, C3H8, C4H10	Organics < 1 pptV, Metals < 1 ppbV				
502	AsH3, PH3	H2O, O2 to < 1 ppb, Metals < 1 ppbV				
503	H2 with up to 1% O2; O2 with up to 2% H2	H2 in O2 or O2 in H2 < 1 ppmV				
602 Covered by this Specification	со	H2O, O2, CO2, Acids, Bases, Organics, Refractory Compounds, Metals <1 ppbV				
702	NH3, C2H7N, C2H8N2, C2H4, C3H6, CH3SiH3, GeH4, SF6, SiH4, H2/SiH4 mixtures	H2O, O2, CO2, NMHCs, Metals to < 1 ppb				
802	SiH4	H2O, O2, CO, CO2, NMHCs, Sulphur compounds, Metals removal < 1 ppb				
804	CO2	H2O, O2, CO, H2 to < 100 ppt; Volatile Acids, Organics, Refractory Compounds to < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppbV				
805	CO2	H2O < 100 ppt; Volatile Acids, Organics, Refractory Compounds to < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppbV				
902	N2, Ar, He, Kr, Ne, Xe, CH4, C2H6, C3H8, C4H10, SF6, Fluorocarbons	H2O, O2, CO, CO2, H2 to < 100 ppt; Volatile Acids, Organics, Refractory Compounds < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppbV				
904	H2, D2, H2-Inerts Mix	H2O, O2, CO, CO2 to < 100 ppt; Volatile Acids, Organics, Refractory Compounds to < 1 ppt; Volatile Bases < 5 ppt, Metals < 1 ppbV				
906	CDA, O2, N2O	H2O, CO, CO2, NMHC to < 1 ppb, Metals < 1 ppbV				

Purifier Regeneration:

Available from any SAES Pure Gas Regeneration Center.



CE Directive:

All MicroTorr Purifiers meet CE directive requirements and come with the CE Marking.





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SAES Pure Gas is ISO9001 certified ISO 9001:2008

